

# Applanix Incorporates Micromachined Sensor Technology

Applanix (Canada) has announced that the latest development in MEMS (Micro-Electro-Mechanical Systems) technology has been incorporated into its line of Position and Orientation System products. The low-noise, micromachined quartz components are compact, durable and designed for use in a high-vibration environment. The sensors are manufactured by BEI Systron Donner Inertial Division (SDID) (CA, USA), a division of BEI Technologies, Inc.

SDID's sensors are micromachined using photolithographic processes producing components that are comparable to small ring laser and fiber optic gyros.

The Applanix line of POS products with MEMS technology is expected to begin shipping in May 2005.

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